## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Mieher, et al. Attorney Docket No.: KLA1P117X1A/

P1151 CIP1

Application No.: 10/785,396 Examiner: Gordon J. Stock Jr.

Filed: February 23, 2004 Group: 2877

Title: APPARATUS AND METHODS FOR Confirmation No.: 6516

DETECTING OVERLAY ERRORS USING

**SCATTEROMETRY** 

## CERTIFICATE OF EFS-WEB TRANSMISSION

I hereby certify that this correspondence is being transmitted electronically through EFS-WEB to the Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450 on September 13, 2007.

Signed: /Mia Mitchell-Haynes/ Typed: Mia Mitchell-Haynes

## AMENDMENT B

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

It is respectfully submitted that the Examiner enters the following amendments in response to the Office Action dated 14 June 2007, a response to which is due 14 September 2007.

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims that begin on page 3 of this paper.

Remarks/Arguments begin on page 9 of this paper.

Replacement Sheets for Figs. 2a~2f, 3b, 5a, 7, and 11d~11f are submitted herewith.

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